

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.	:	(To Be Assigned)	Confirmation No.	:	(TBA)
		PCT/JP2004/009026			
First Named Inventor	:	Hiroshi KANNAN			
Filed	:	December 27, 2005			
TC/A.U.	:	(To Be Assigned)			
Examiner	:	(To Be Assigned)			
Docket No.	:	010986.57272US			
Customer No.	:	23911			
Title	:	Plasma Generation Method, Cleaning Method, and Substrate Processing Method			

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please enter the following amendments to the specification and claims, as amended by way of Annexes to the International Preliminary Examination Report for PCT/JP2004/009026, prior to the examination of the application during the U.S. National Phase.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 22 of this paper.